

ABSTRACT OF THE DISCLOSURE

Method of Manufacturing a Perpendicular Magnetic Recording
Medium, Method of Manufacturing a Substrate for Said Recording
5 Medium, a Medium and a Substrate Manufactured by the Methods

An object of the present invention is to provide a method of
manufacturing a perpendicular magnetic recording medium and a substrate
for the medium, in which abnormal protrusions on an underlayer made of a
10 Ni-P alloy are automatically eliminated while maintaining a flat surface with
high accuracy on the underlayer, and appropriate texture traces remain to
promote magnetization alignment in the vertical direction in a perpendicular
magnetic recording medium without adversely affecting the magnetization
alignment.

15 In the method, texture processing is carried out on the underlayer 6
made of a Ni-P alloy on a nonmagnetic base plate 2 using a polishing tape
34 while supplying mixed slurry of a surfactant and abrasive grains of
polycrystalline diamond, and then, texture polishing is carried out on the
underlayer processed by the texture processing, using a polishing tape 36
20 while supplying slurry containing an abrasive material 38 and an organic
acid until the surface of the underlayer is polished to an arithmetic mean
roughness Ra of at most 0.5 nm, preferably in the range of 0.05 nm to 0.2
nm.

25 Selected drawing: Fig. 2.